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- (54) Title of the Invention: Sample exchange device for scanning electron microscope
- (21) Application No.: 57-42991
- (22) Filing Date: Mar. 26, 1982
- (72) Inventor: ISHIMORI Yoshio
- (72) Inventor: SHIBUKI Yoichi
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- (57) Claims

Sample exchange device for scanning electron microscope, [said device] comprising a plurality of sample exchange chambers arranged in communication with a

sample chamber and a vacuum valve; and means for preliminary evacuation of each individual sample exchange chamber, and designed such that while a sample exchange chamber is being subjected to preliminary evacuation in preparation for introduction of a sample into the sample chamber via said sample exchange chamber, another sample may be observed.

Brief Description of the Drawings

The drawing illustrates an embodiment of the invention.

1: lens barrel; 2: sample chamber; 3: stage; 4a, 4b: sample exchange chambers; 5a, 5b, 6a, 6b, 12a, 12b, 13a, 13b, 14, 15, 16, 17, 18: vacuum valves; 7a, 7b: sample exchange rods 11: rotary pumps; 9a, 9b: evacuation lines; 10: diffusion pump; Ha, Hb: sample holders.

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審查請求 未請求

(全 頁)

対走査電子顕微鏡等の試料交換装置

賢 昭57-42991

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